

From Fundamental Detector Research to Industrial Embedded Power Device Technology Development

Joint Instrumentation Seminar
DESY, Hamburg University and XFEL
Colloquium in honor of Prof. Gunnar
Lindström's 80th birthday

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Abstract

- Following the "More than Moore" paradigm, restructuring of parts of the semiconductor industry is currently taking place: Added value generation is being sought in the chip-level integration of devices offering unique functionality with dense CMOS logic, as opposed to the former shrink approach towards ever smaller structure sizes (Moore's Law).
- An example is presented in the area of embedded power devices that are capable of handling voltages up to several times 10 Volts in a 1.5 Volt core voltage analog/mixed-signal logic platform. Key aspects to be considered in the technology development are device performance factors like specific on-resistance, robustness (e.g. safe operating area and electrostatic discharge), reliability, latch-up, and substrate noise effects. Results from TCAD process and device simulation, device characterization, and statistical data analysis are presented.
- The speaker gives account of the knowledge and qualifications acquired during his diploma and PhD time in Prof. Gunnar Lindström's group on "Detector Research & Development" (formerly "Gruppe Nukleare Meßtechnik") whenever useful reference to his current field of work can be made. An industry perspective is thus provided on the value of fundamental research and the qualifications required for a successful career in the semiconductor industry.

- Infineon: The Company

- Embedded-Power Device Development at Infineon Dresden

- Anecdotal References to “Good Old Times” at Nukleare Meßtechnik

Infineon at a Glance

The Company

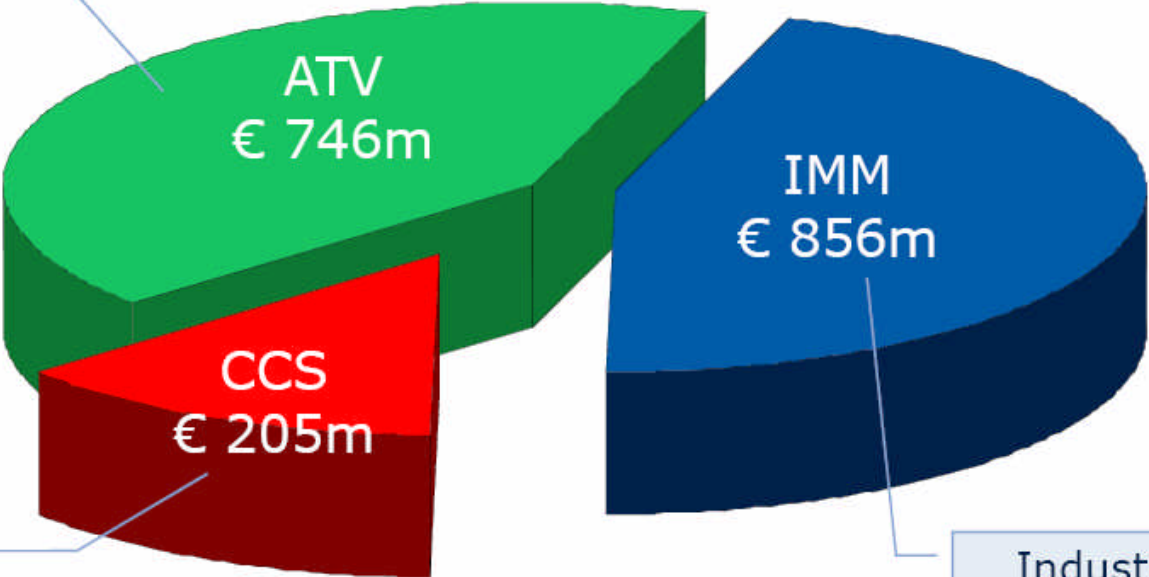
- Infineon provides semiconductor and system solutions, focusing on three central needs of our modern society: **Energy Efficiency, Mobility and Security**
- Revenue in FY 2010*: 3.295 billion EUR
- 25,119 employees worldwide (as of April 2011)
- Strong technology portfolio with about **15,400** patents and patent applications (as of Feb. 2011)
- More than **20 R&D locations**
- Germany's largest semiconductor company

*Note: Figures according to IFRS with Wireline and Wireless as discontinued operations; as of September 30, 2010

Revenue Split by Division

6-months FY 2011 revenue split

Automotive



Chip Card & Security



Industrial & Multimarket



Infineon Semiconductor Technology Portfolio



Technology portfolio fits needs of logic and power applications

Power/Analog



incl. Green Robust

Analog Bipolar: DOPL, Ax, BIPEP, B4C	DMOS: Low Voltage Trench Mosfets (OptiMOS)
Analog BICMOS: B6CA, B6CA-CT, B7CA, SPT170 500 - 350nm HV-CMOS-SOI	HV-DMOS: Superjunction MosFET (CoolMOS)
Smart Power : 1200-130nm BIP/CMOS/DMOS SPTx (Automotive, EDP) (BCD)	IGBT: Trench IGBT 600-6500V, rev. cond., fast recov. diodes
Smart : CMOS/DMOS, SMARTx, (SmartMOS) MSMARTx, SSMARTx Opto-TRIAC	SiC: Diode; MOS/JFET
all of them adopted for automotive and industrial requirements	

MEMS/Sensors



Analog ICs: B6CA, B7CA Coreless Transformer	Pressure: BxCSP, TIREPx
Magnetic: BxCAS, C9FLRN_GMR	Silicon-Microphones
Opto: OP-DI, OP-TR, OP-C9N, μ -modules	

CMOS



Digital CMOS: 800nm - 65nm Technology Nodes (Platform <180nm incl. RF, AMS)
Analog/Mixed Signal: 500nm - 180nm Technology Nodes (CxNA)
eNVM: EEPROM: IMEMR, C9FL, OTP: C5OP (Automotive)
eFlash/EEPROM: 250nm - 65nm CxFL (Chip Card), CxFLA, CxFLN (Automotive)
HV-CMOS: 130nm, C11HV

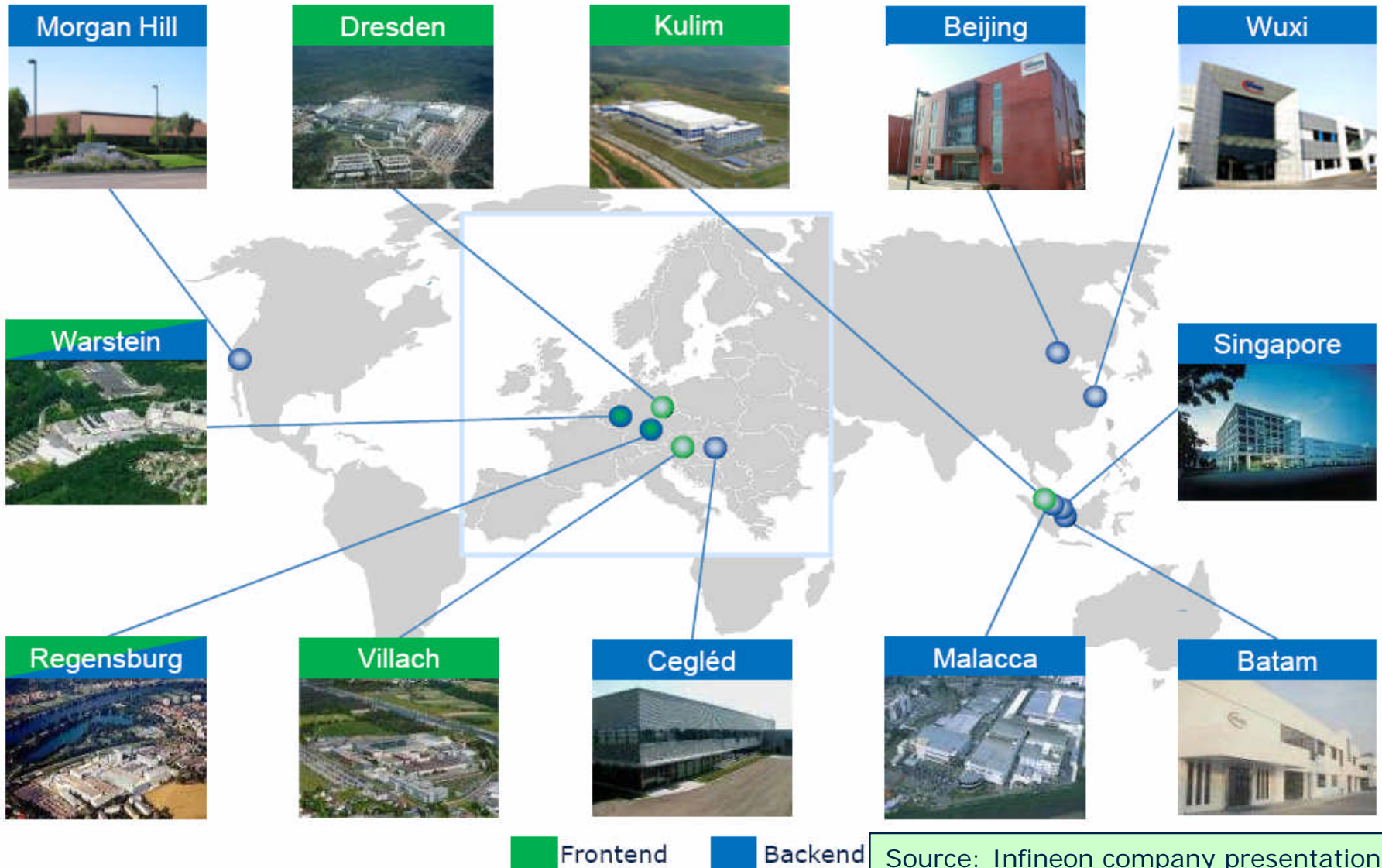
RF/Bipolar



RF BICMOS: 25GHz - 100GHz: B6HFC, B9COPT, B10C	SiGe: B7HFM, B7HF_SLC, B7HF200
Bipolar IC: 2GHz...200GHz RF-Bipolar: BxHF	RF Switches: C7NP, C11NP
HiPAC: Al/Cu Integrated Passives P7Mxx, P7Dxx, P8Mxx, P9Mxx	
Bipolar/Discretes/MMIC:	SiGe: B7HFD/M, B7HF_SD
RF-Transistors NF-TR; BxHF(D/M),	RFMOS: HFM
Power Amplifier: LDMOS, LDxM, LDxIC, LD9AB	PIN: DxP
Diodes: NF-DI, Tuner: DxT, Schottky: DxS	

Source: Infineon company presentation
May 3rd, 2011, www.infineon.com

Infineon – Worldwide Production Sites Frontend and Backend



Frontend Backend

Source: Infineon company presentation
May 3rd, 2011, www.infineon.com

Infineon Technologies Dresden (IFD)



12/93 Siemens AG decided to build a first-class semiconductor fab in Dresden

10/95 Production start 200mm fab



02/98 Joint Venture with Motorola for first 300mm pilot-line worldwide

04/99 Carve-out of Semiconductor division from Siemens
=> Foundation of Infineon AG:
Siemens Microelectronics Center Dresden becomes Infineon Technologies Dresden



05/00 Laying of the cornerstone for first 300mm fab worldwide

05/05 Opening of Infineon Research and Development Center (RDC)
Opening of Center Nanoelectronic Technologies (CNT),
Public Private Partnership (PPP) between
FraunhoferGesellschaft, AMD and Infineon



05/06 Infineon carved-out its Memory Products Business
=> Foundation of Qimonda



03/08 Infineon Dresden becomes an entire Logic site

Front-End Production at Infineon Dresden

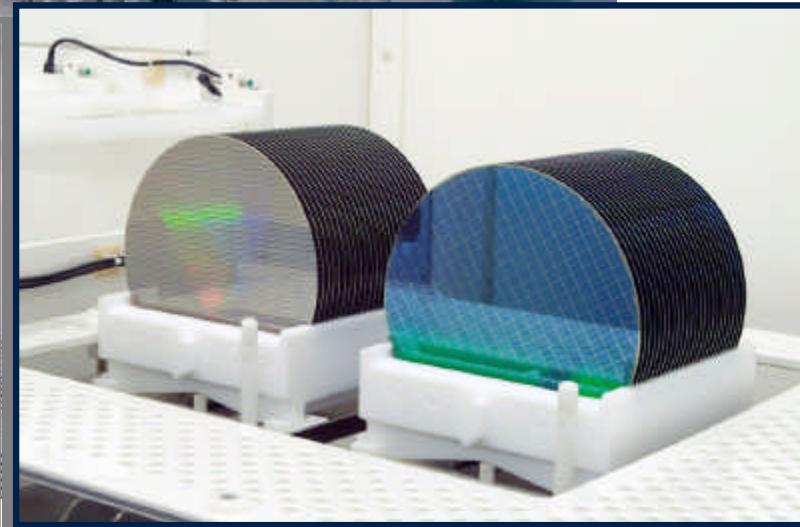


State-of-the-art semiconductor processing line for large-scale integration of electronic circuits on 200 mm silicon wafers

0.25 μm to 90 nm technology nodes

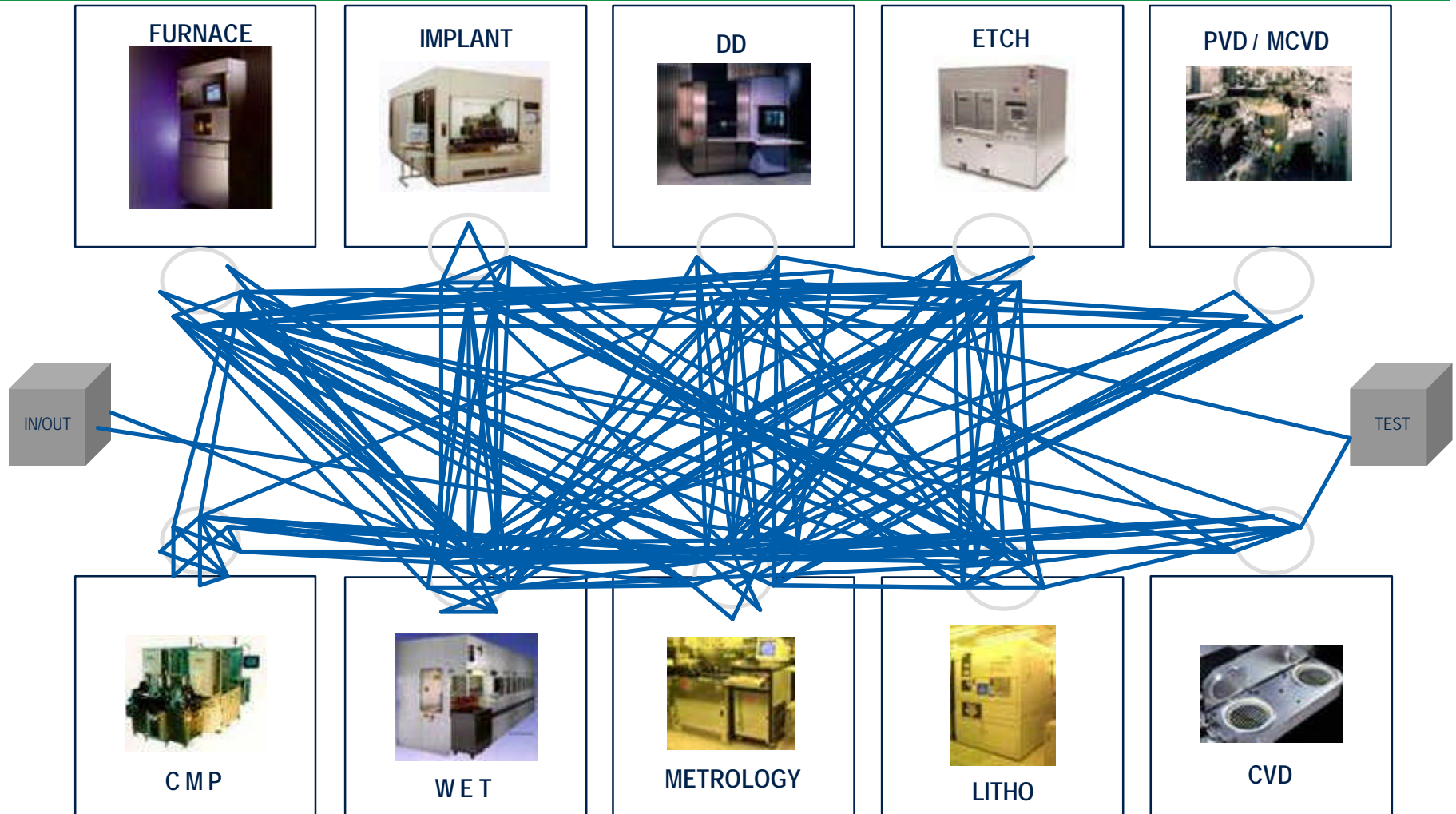
Aluminum and copper metallization

Research and development site



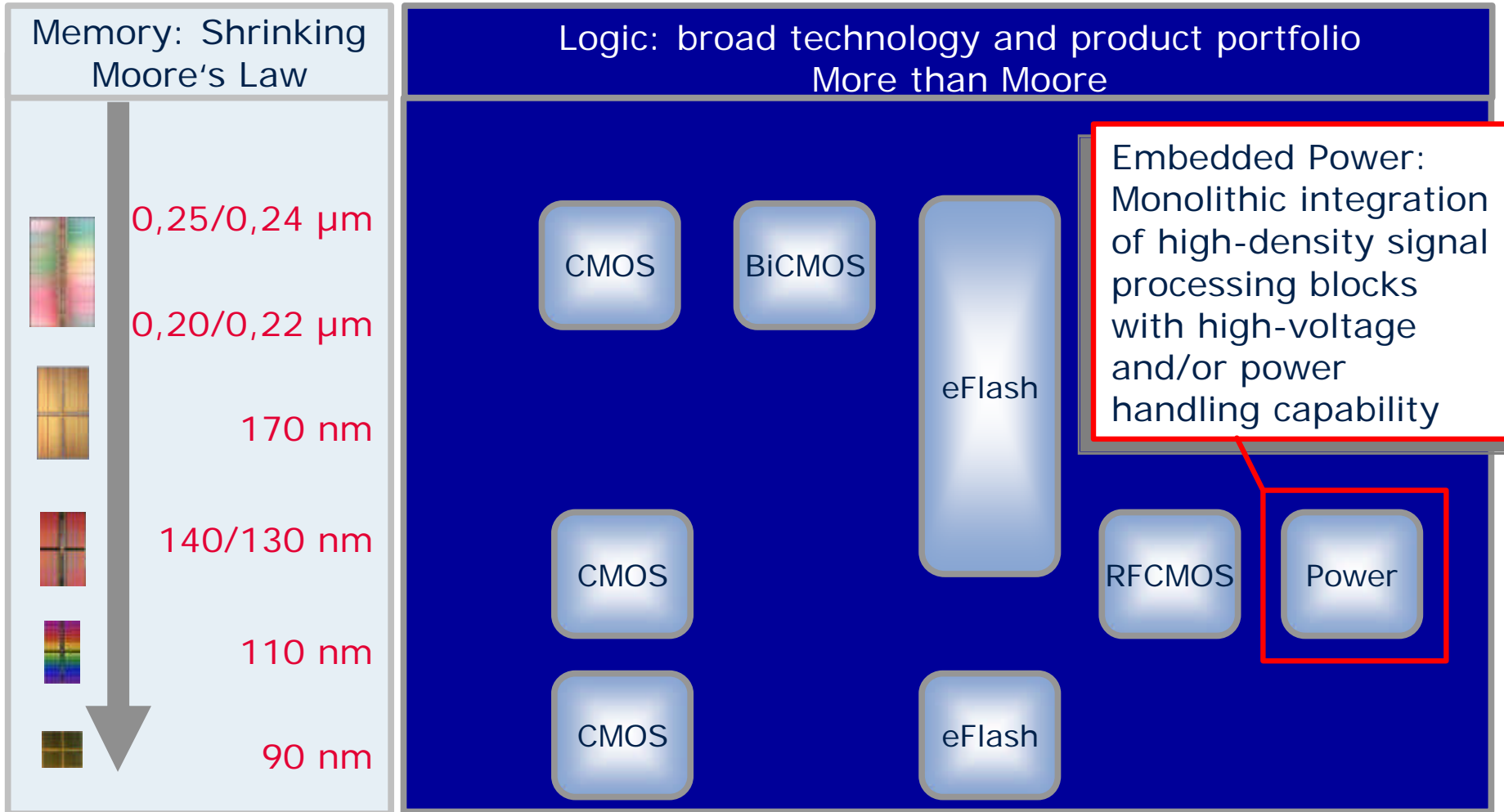
Production Complexity

Several hundred process steps for each wafer



Example: Pilot-Line featuring all necessary tools and processes for a product cycle

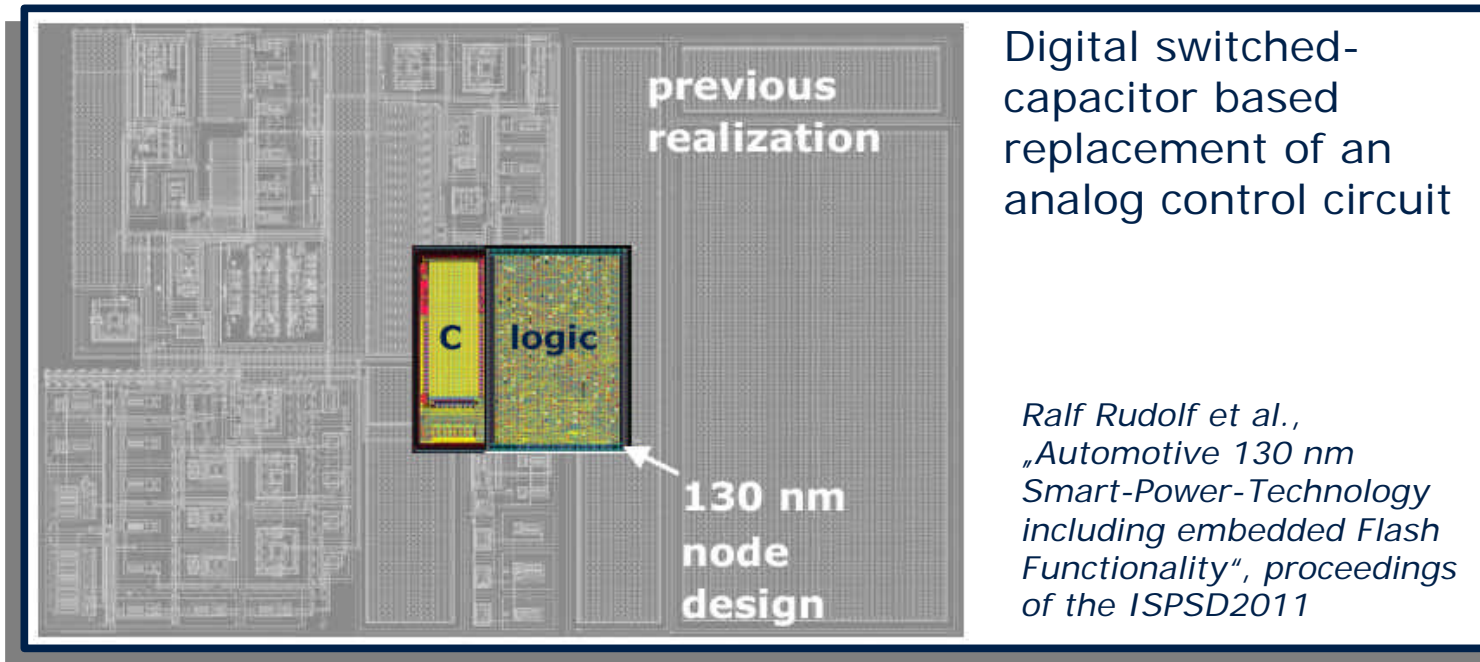
„More than Moore“



Value Proposition for Embedded Power @ IFD

a): Gate Density

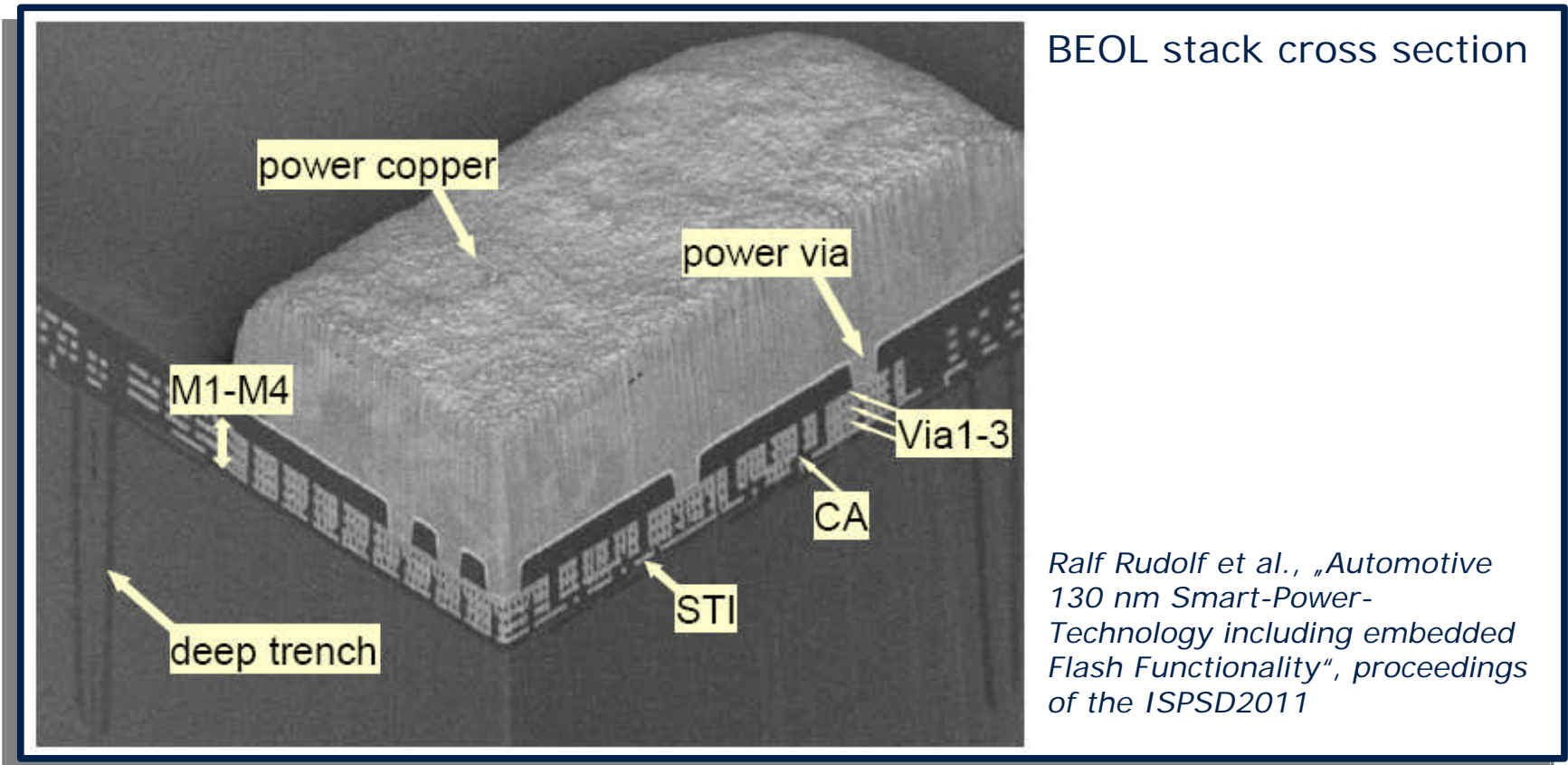
- ❑ Address the industry trend towards higher on-chip functionality as a key differentiator in the IC market
- ❑ Re-use of intellectual-property (IP) blocks for reduced time-to-market
- ❑ Area shrink (e.g. by realizing analog functions in the digital domain)



Value Proposition for Embedded Power @ IFD

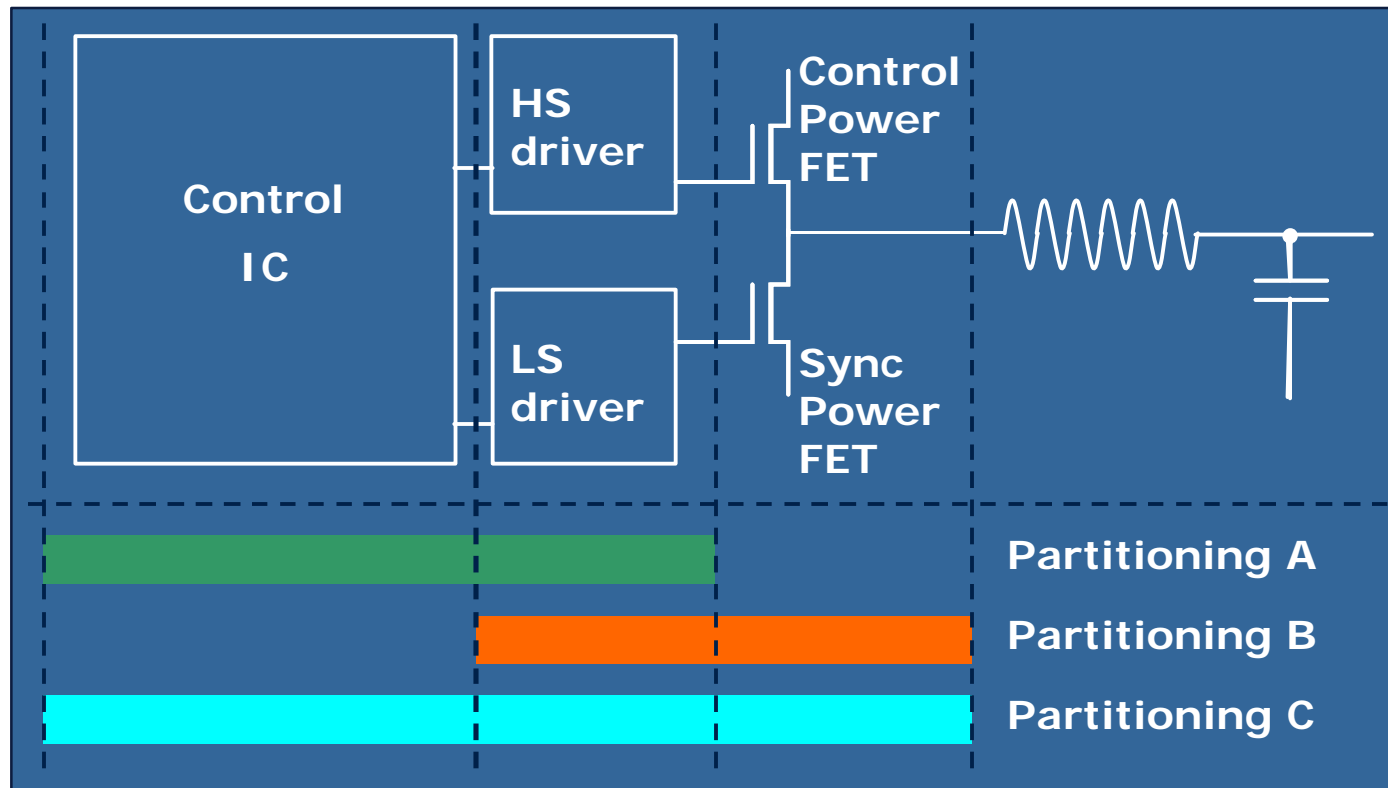
b): Deep-Submicron Process Line

- ❑ Feature size, process tolerances
- ❑ Yield stability / defect density control
- ❑ All-copper metalization for optimum thermal management



Fields of Application for Embedded-Power Technologies

Example: Regulated-voltage generation using buck converter and/or synchronous rectification (SR)



Depending on cost factors, performance factors, and target market requirements, the choice of the appropriate system partitioning decides on the competitiveness of the product.

IFD Research and Development Activities for Embedded-Power Technologies



- TCAD (Technology Computer Aided Design)
 - detailed representation of the IFD process flows with in-depth unit-process background information
 - delivering reliable pre-silicon electrical device characteristics
- Highly automated testchip layout and characterization
- Shared reticle program, dual/quad multi-level reticle mask options
- Efficient unit process development
- Competitive flow-factor for development lots
- Various lab characterization capabilities including high-power SMUs and TLP/SOA set-up

Process Blocks and Features of C11HV

C11HV process module
p-type substrate
shallow trench isolation
HV isolation
HV devices
logic wells
gate stack (oxide and poly)
extension/halo implants
spacer
source/drain implants
silicide formation
4 levels Cu metallization
top metal and passivation

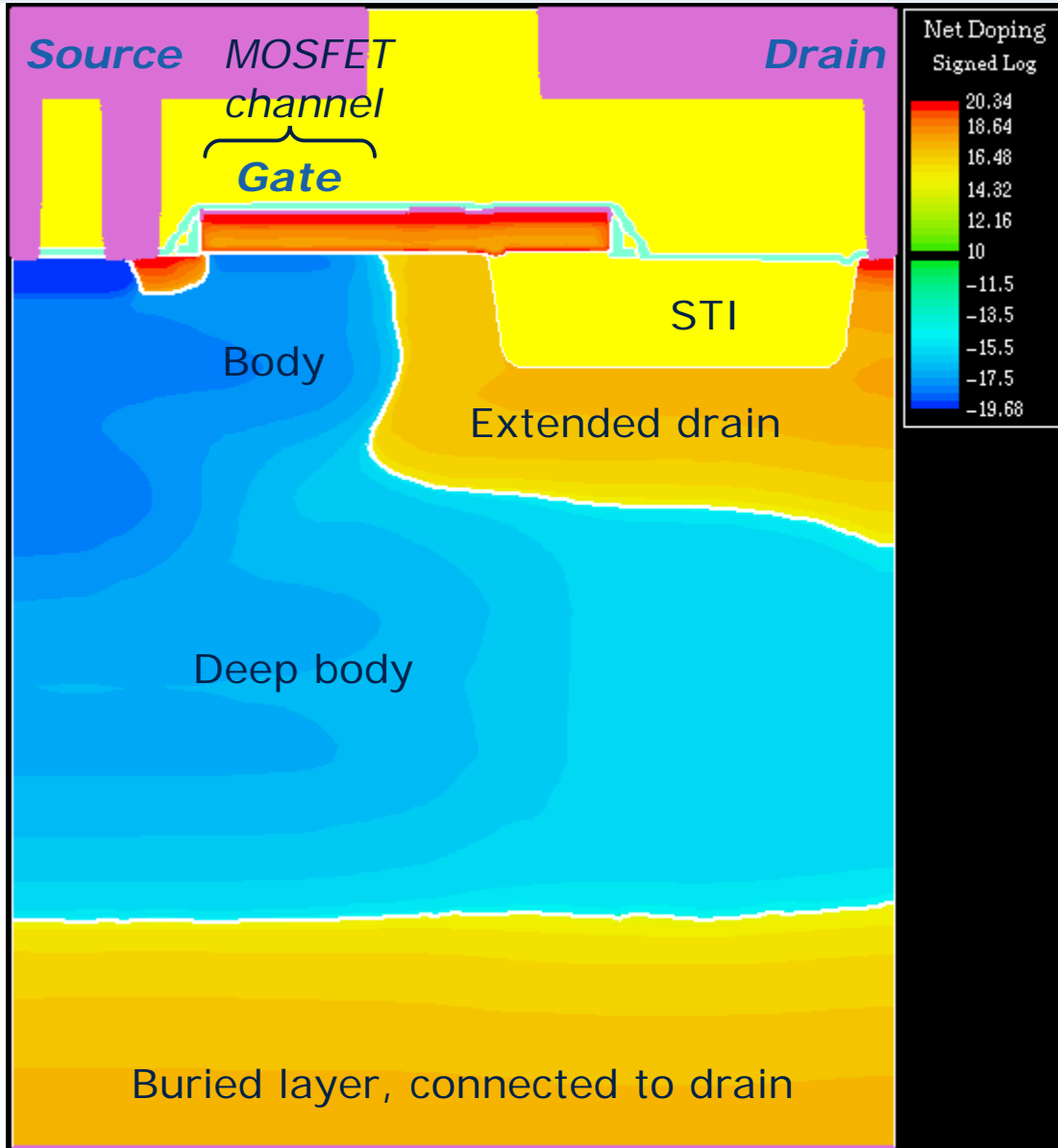
Overview High Voltage Devices

- 12V HVNMOS/PMOS Power Transistors for High-Current Applications, $R_{dson} 4 \text{ m}\Omega \cdot \text{mm}^2$
- 24V HVNMOS/PMOS Power Transistors for Gate Driver Applications
- 24V HVNMOS/PMOS w separate Body for analog and level shifter applications. HVNMOS fully isolated
- 20V pnp Transistor
- HV ESD concept based on self protecting power devices, Diodes and active clamps
- passive Elements (Poly Resistors and Metal Capacitors)
- Well Isolation for floating Low Voltage circuitry

Determining the recipes for the newly introduced process modules is the main deliverable of the technology development group!

Lateral High-Voltage (HV) Device Concepts

24V Drain-Extended MOSFET



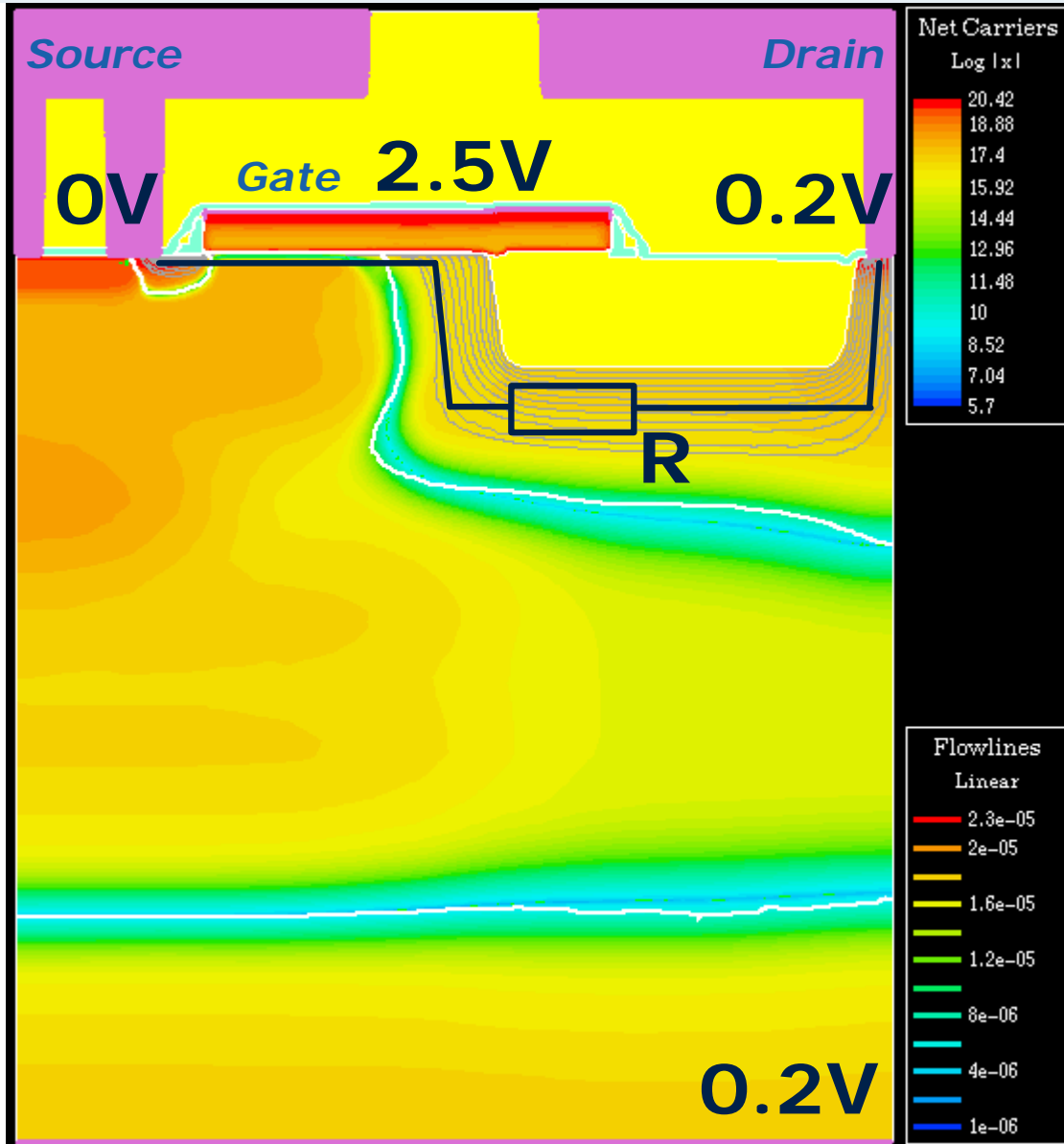
n-type Silicon

p-type Silicon

A 2.5 V gate-oxide from the base process is used for the channel region (5.2 nm).

Therefore, the high drain potential (24V) must be well shielded from the gate!

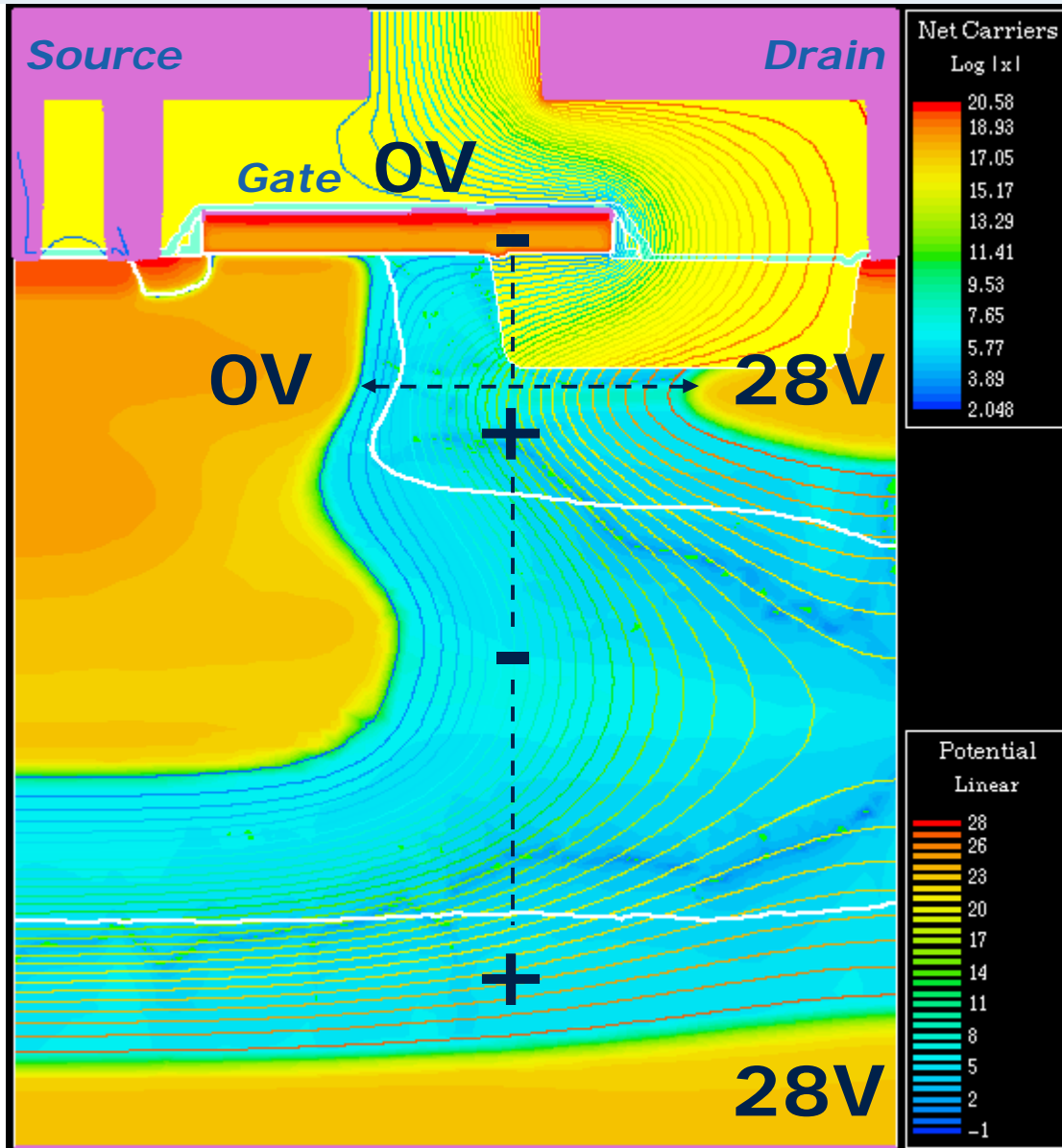
Basic HV Device Operating Conditions On-State



The on-state resistance is determined by the doping in the drain extension.

-> minimizing the on-state switching resistance requires maximum doping in the drain extension.

Basic HV Device Operating Conditions Off-State



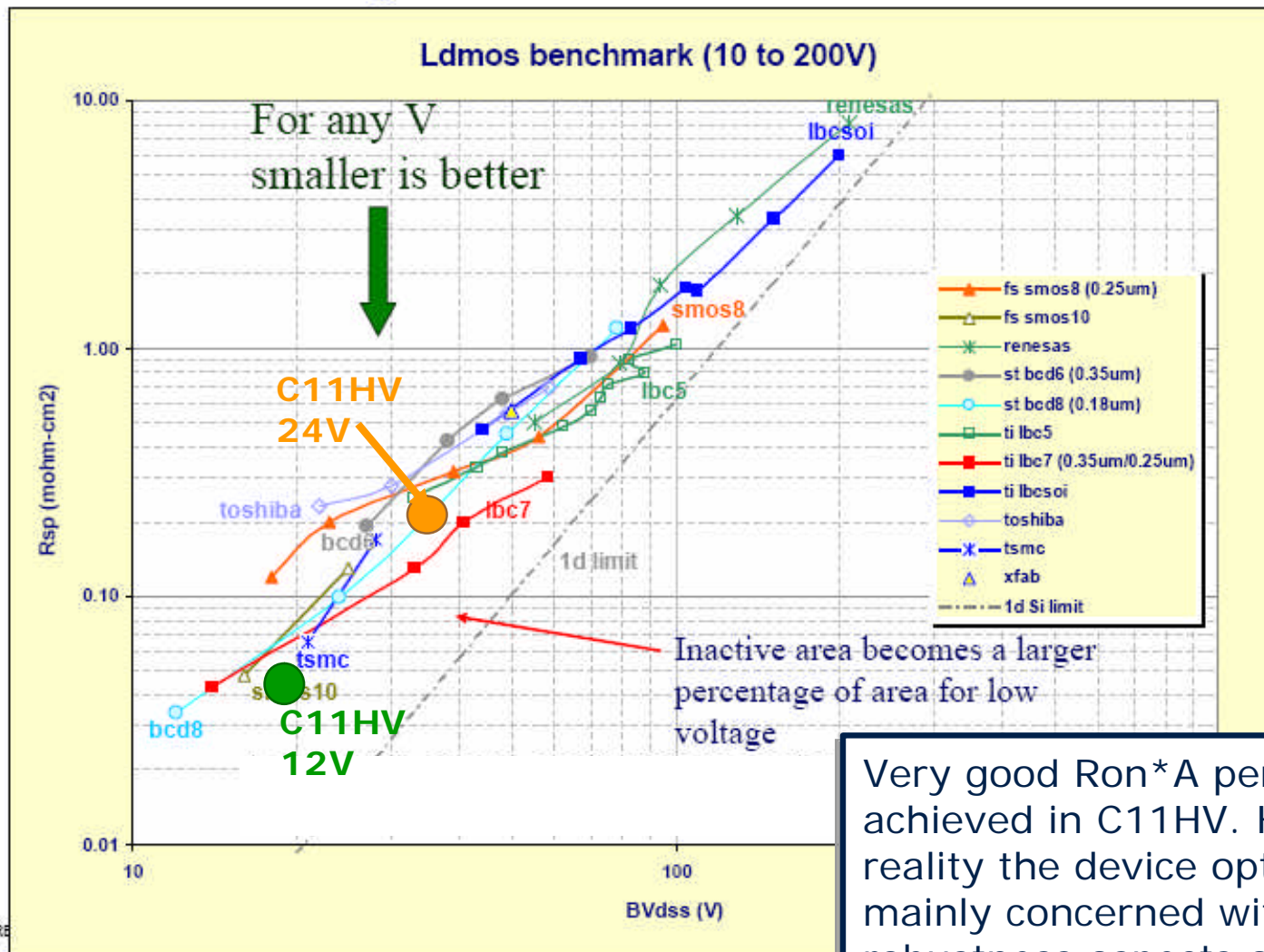
However, high doping in the drain extension limits the breakdown voltage!

Mirror space-charge principles are used to reduce the electric field strength in the drain extension region.

If charge matching is optimized the horizontal drain / body region mimics a p-i-n diode, allowing minimum lateral extent of the structure.

Drain-Extended MOSFET On-Resistance Benchmark

Integrated LDMOS Performance

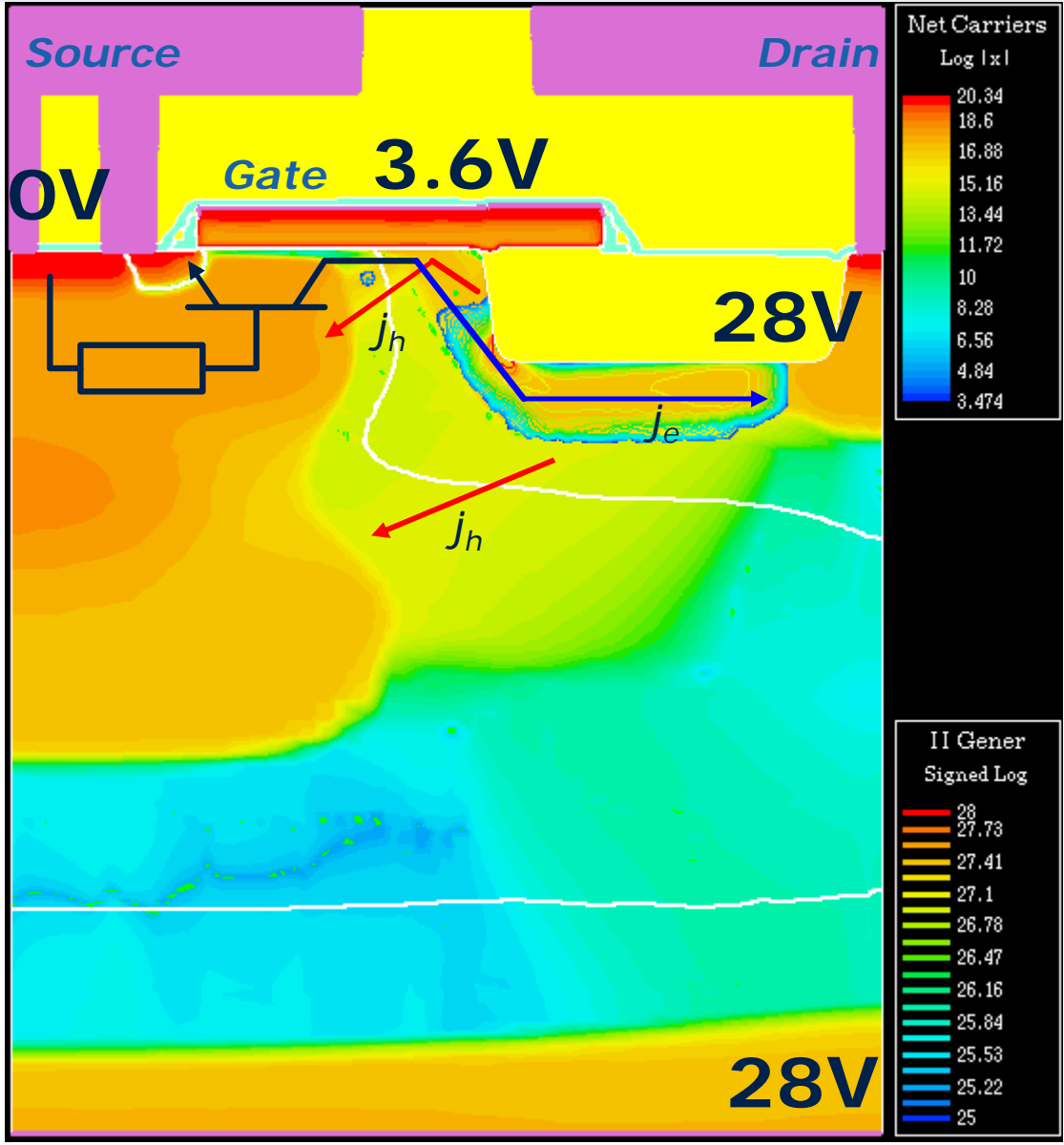


Very good $R_{on} \cdot A$ performance is achieved in C11HV. However, in reality the device optimization is mainly concerned with device robustness aspects and/or safe-operating area (SOA).

Basic HV Device Operating Conditions

Hot-switching State

$$V_{ds} * I_{ds} \approx \text{kW/mm}^2$$



This switching state should be kept as short as possible since a lot of power is dissipated

- > poor energy efficiency
- > thermal failure

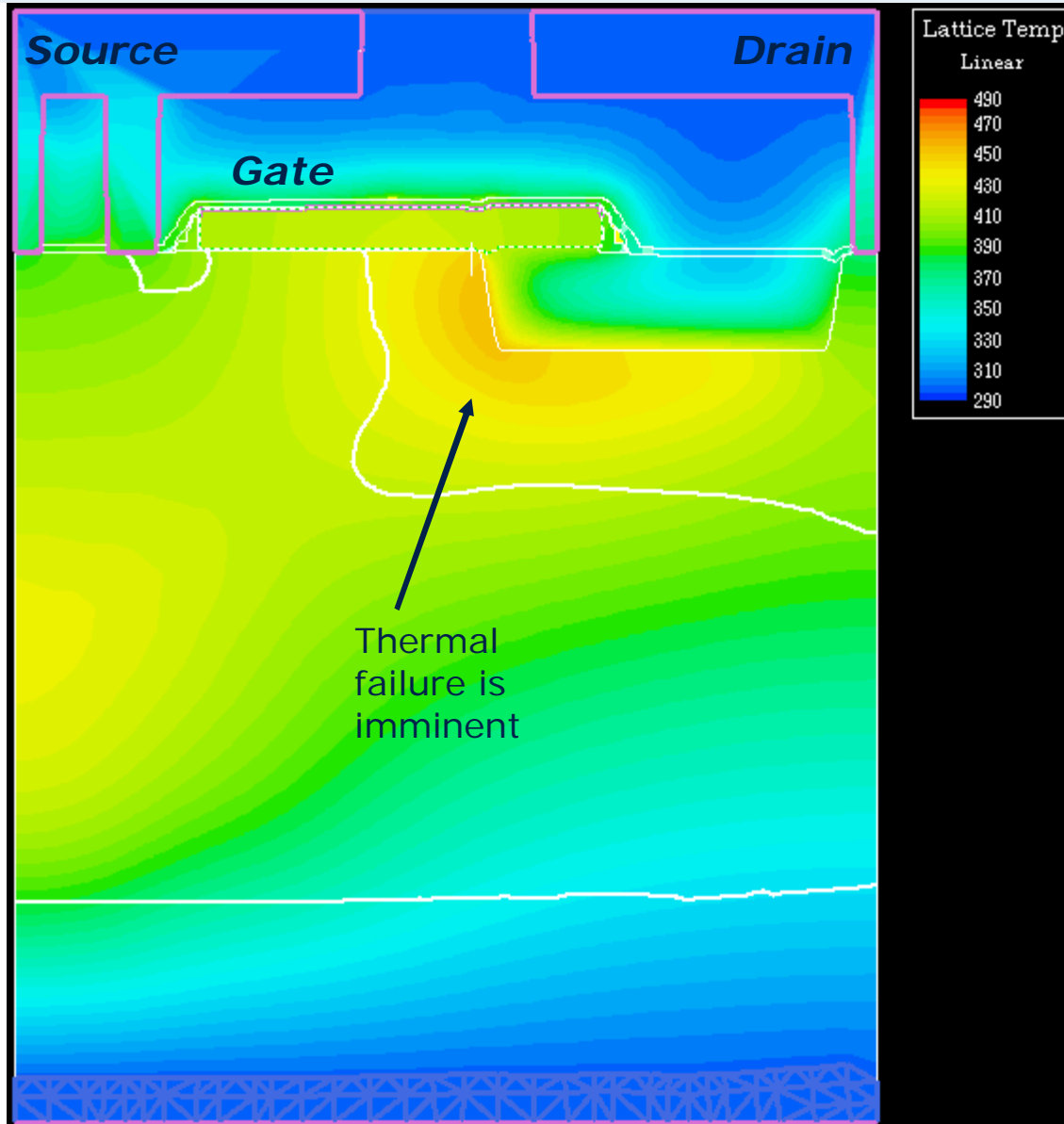
High electric fields in the drift region lead to impact-ionization (II) carrier multiplication

- > hole currents are biasing the inherent npn
- > hot-carrier effects, device parameter drift / reliability

Safe operating areas (SOA) for V_{ds} and I_{ds} can be defined based on

- > thermal failure
- > electrical npn triggering
- > reliability

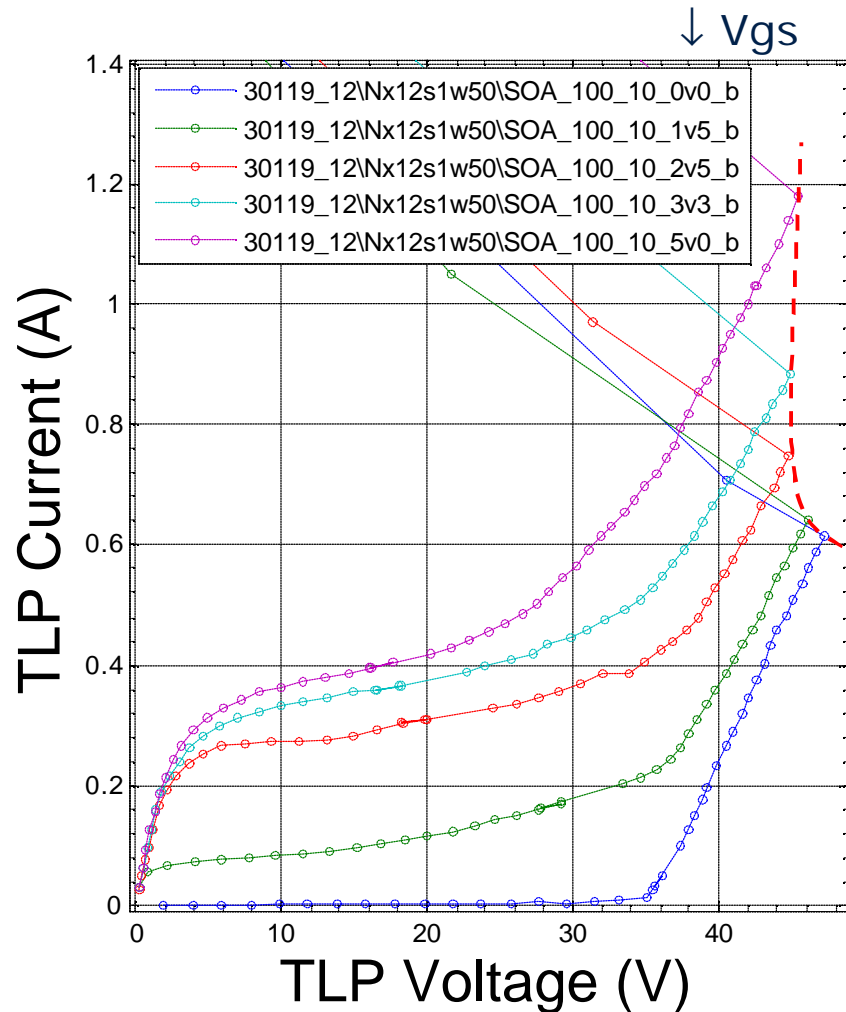
Lattice Temperature after 100 ns (Thermal SOA, medium switching times)



Electro-thermal TCAD simulations are quite helpful for optimizing the device robustness.

The metallization plays a vital role in heat conduction away from the active device region.

Transmission-Line Pulse Characterization (Electrical SOA, short switching times)



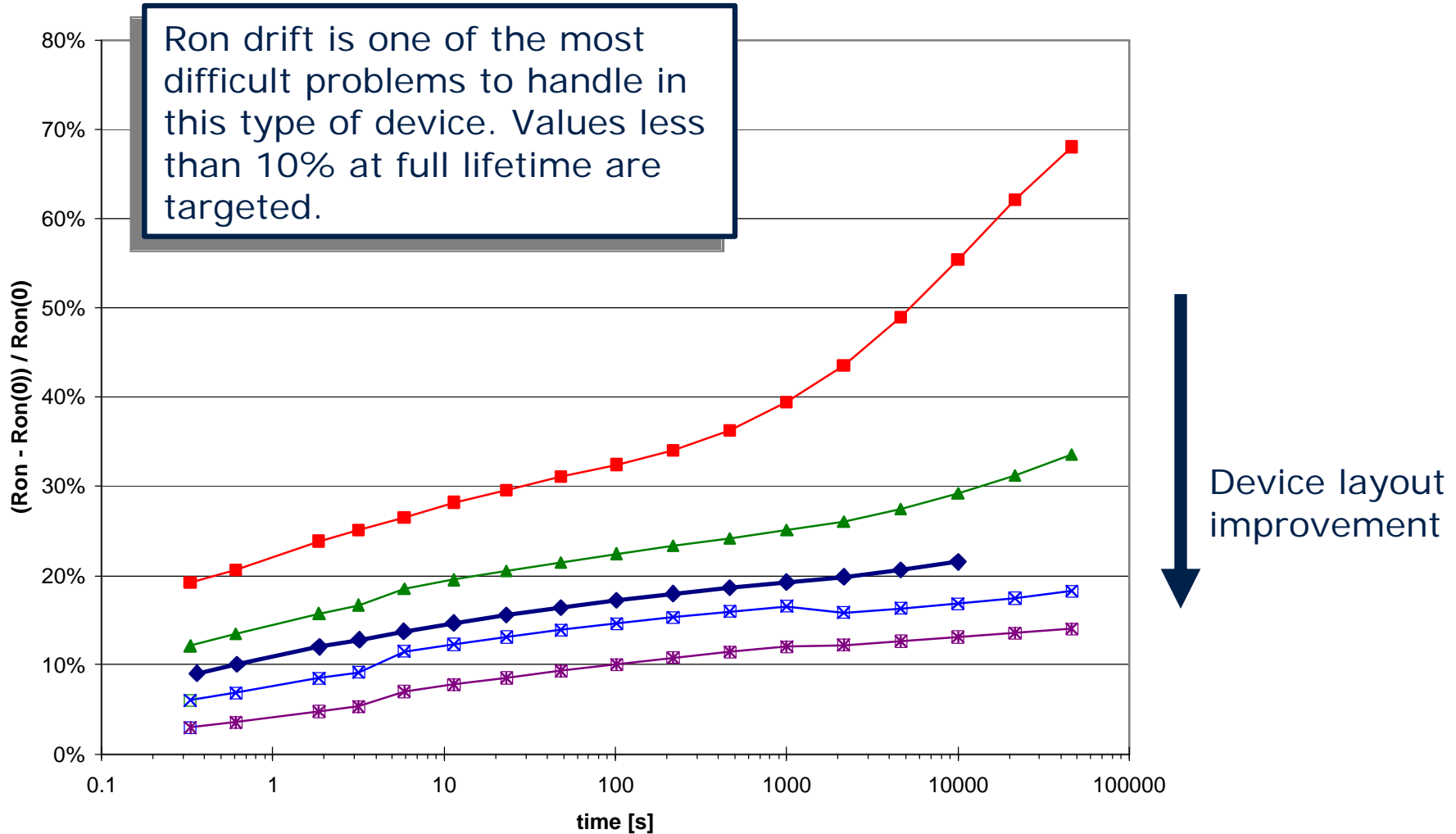
Transmission-line pulsing (TLP) is typically a 100-ns square-wave pulsed IV characterization. This is a good indication of device behavior under ESD stress.

ESD qualification must be withstood at any pin of the IC (e.g. human-body model: 100 pF charged to 2 kV discharge through 1.5 kOhm).

The failure is due to electrical triggering of the parasitic npn.

Maximizing the failure current is an optimization target for output drivers.

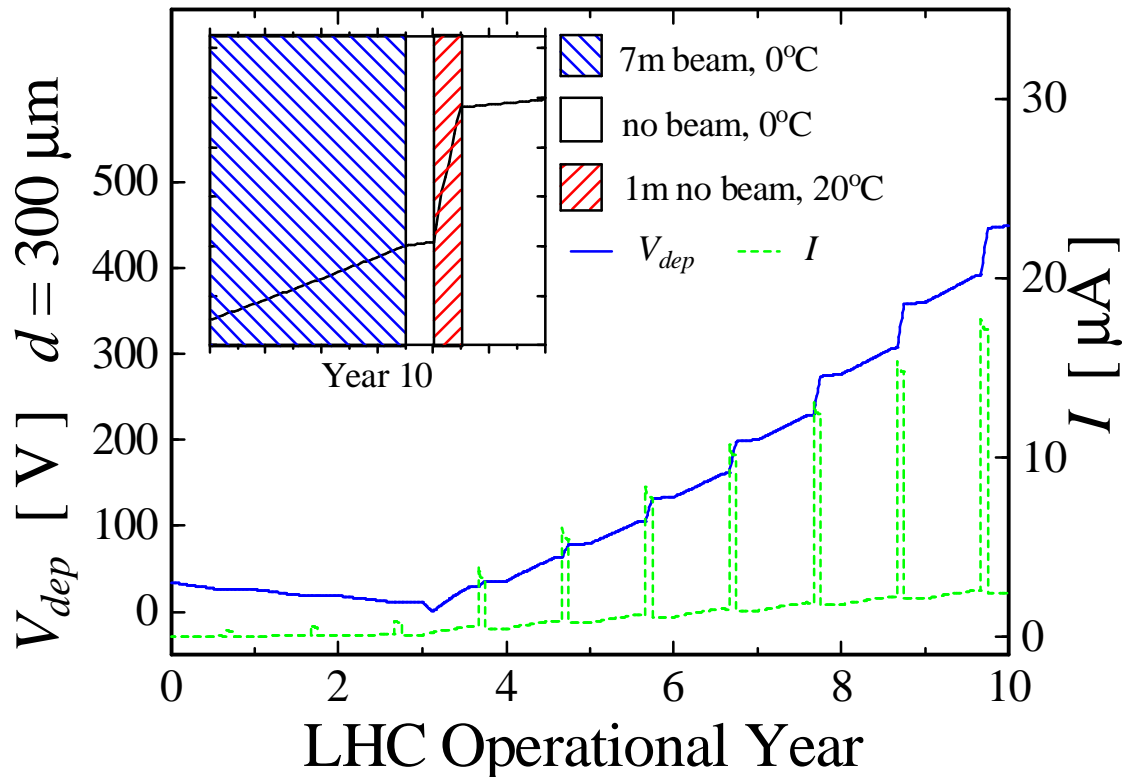
Ron Drift (Reliability SOA, life-integrated switch time)



Lessons Learnt at "Nukleare Meßtechnik" Lifetime Projections, Customer Orientation

Results for the Strip Layer at Radius 30 cm

$F_{eq} = 1.7 \times 10^{13} \text{ cm}^{-2}$ per year at full luminosity.



Source: H. Feick, PhD thesis

Our efforts to predict the operating lifetime of silicon detectors in the LHC experiments clearly addressed the customer's need for a solid decision basis in planning the overall experiment.

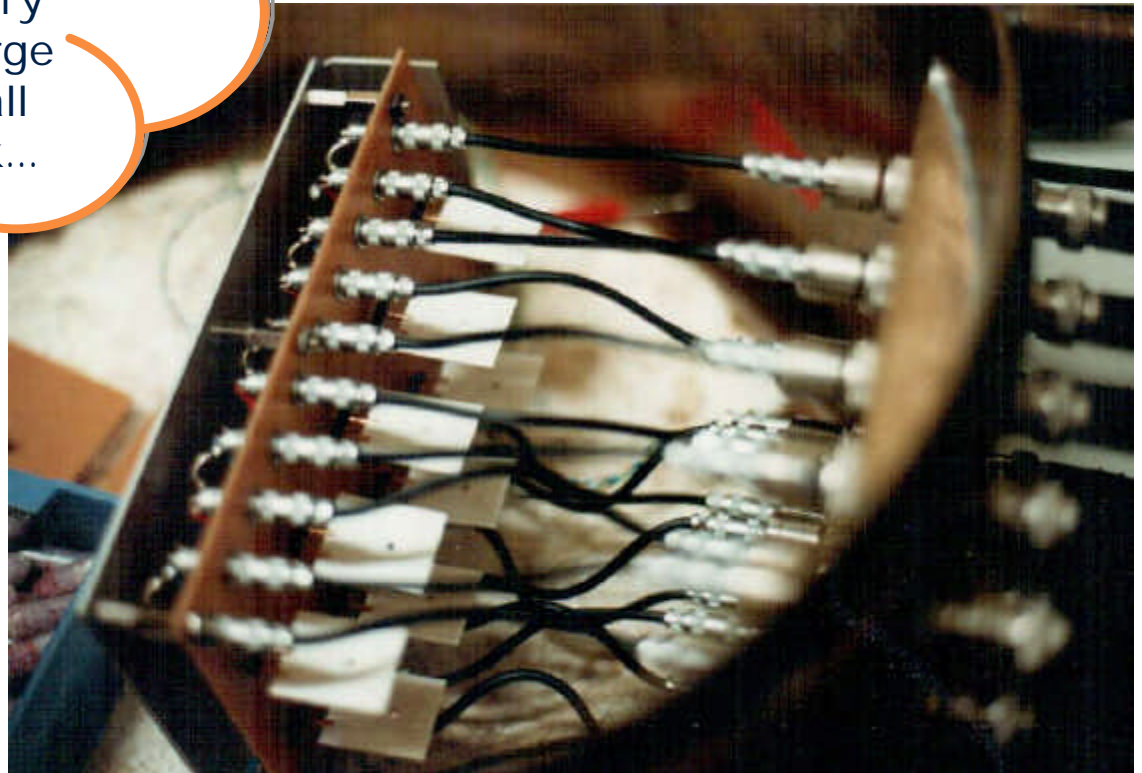
Such type of customer orientation is also paramount for business success in the semiconductor industry.

Lessons Learnt from Gunnar: Part 1

Large Statistics Improve Prediction Quality

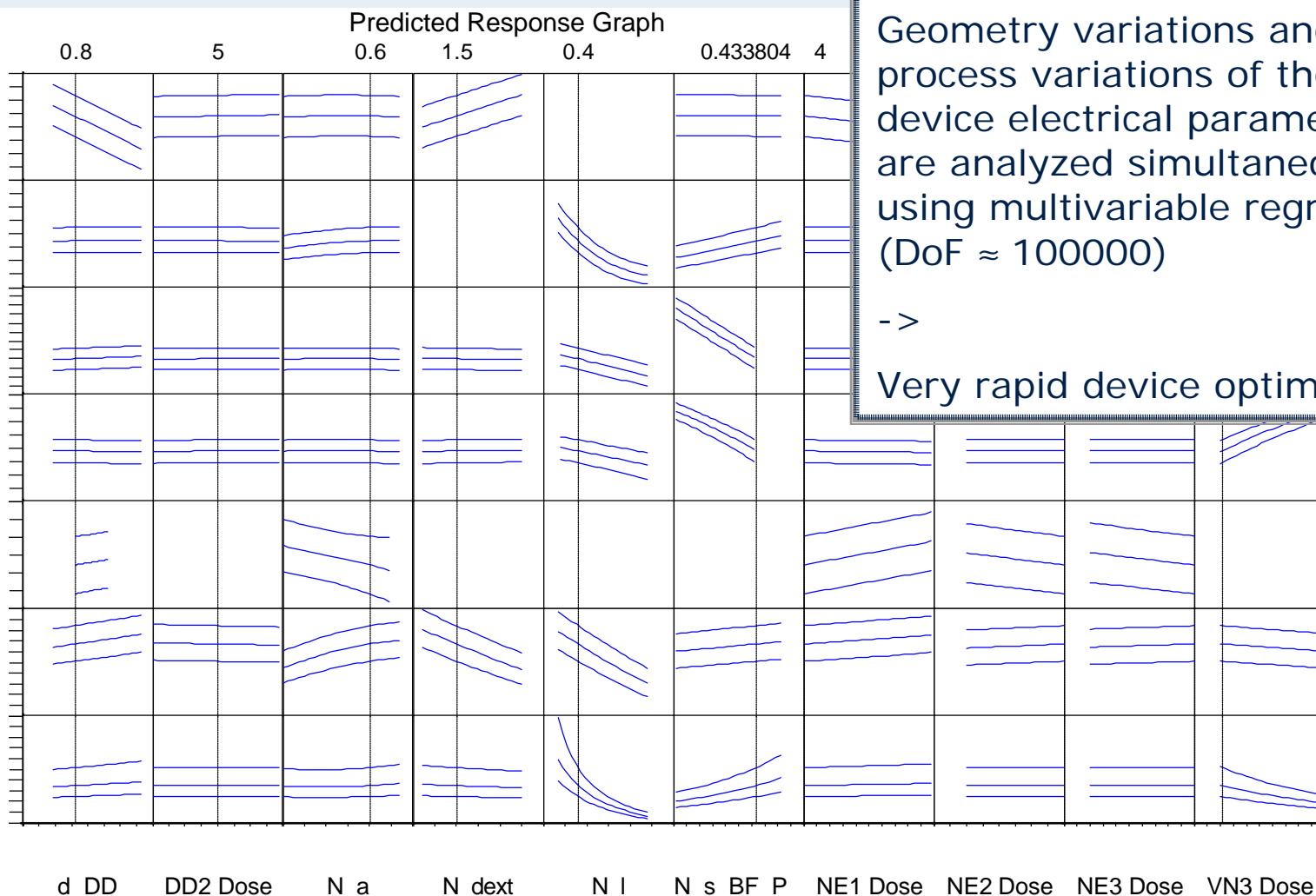
If only we had better statistics -

Those guys from industry must have incredibly large databases containing all the knowledge we seek...



This is how we tried to maximize our statistical database at „Nukleare Meßtechnik“ around 1997

Statistical Modeling and Optimization of the C11HV 24V Device



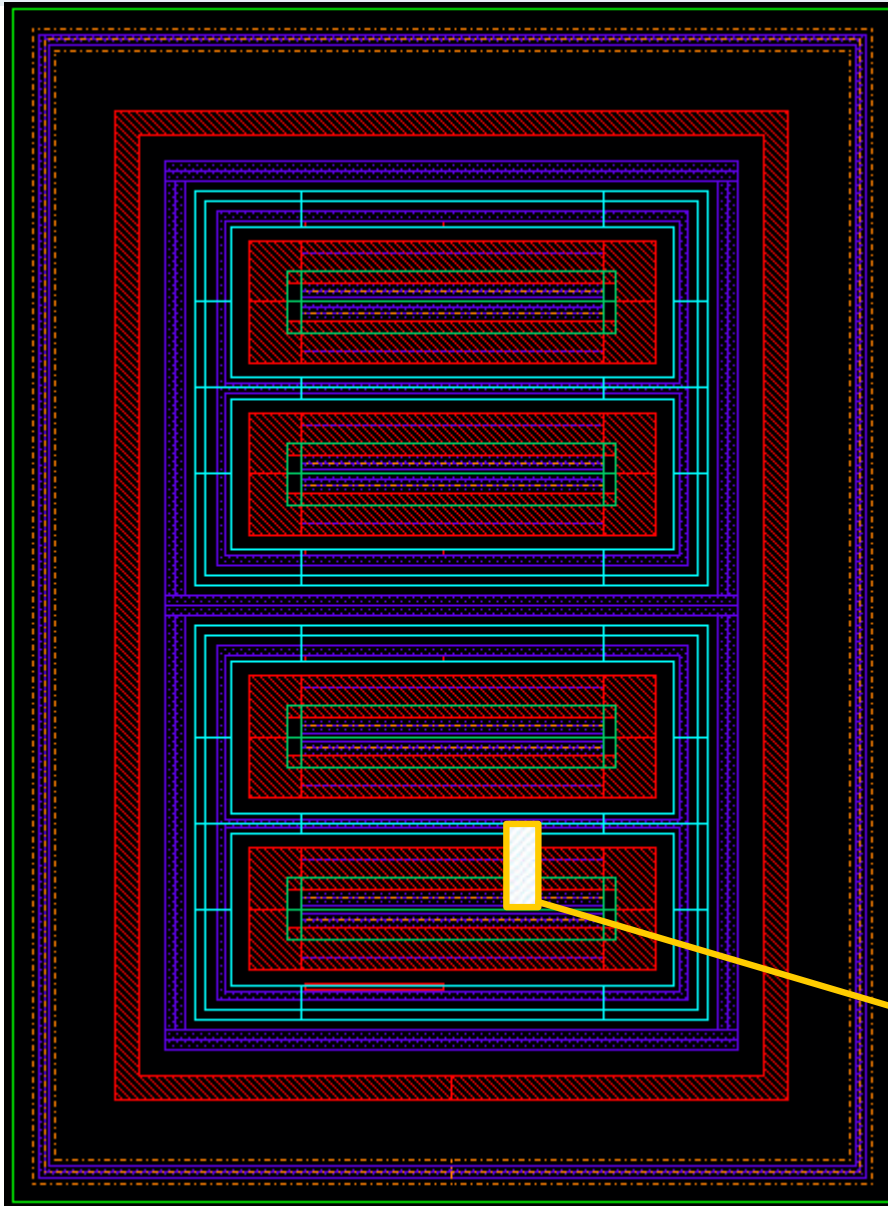
Geometry variations and process variations of the device electrical parameters are analyzed simultaneously using multivariable regression (DoF \approx 100000)

->

Very rapid device optimization

It is true, we can generate and analyze tremendous amounts of data. Still, I am not aware of information in our databases explaining the mysterious type inversion and annealing effects in Silicon detectors.

C11HV Device Layout View



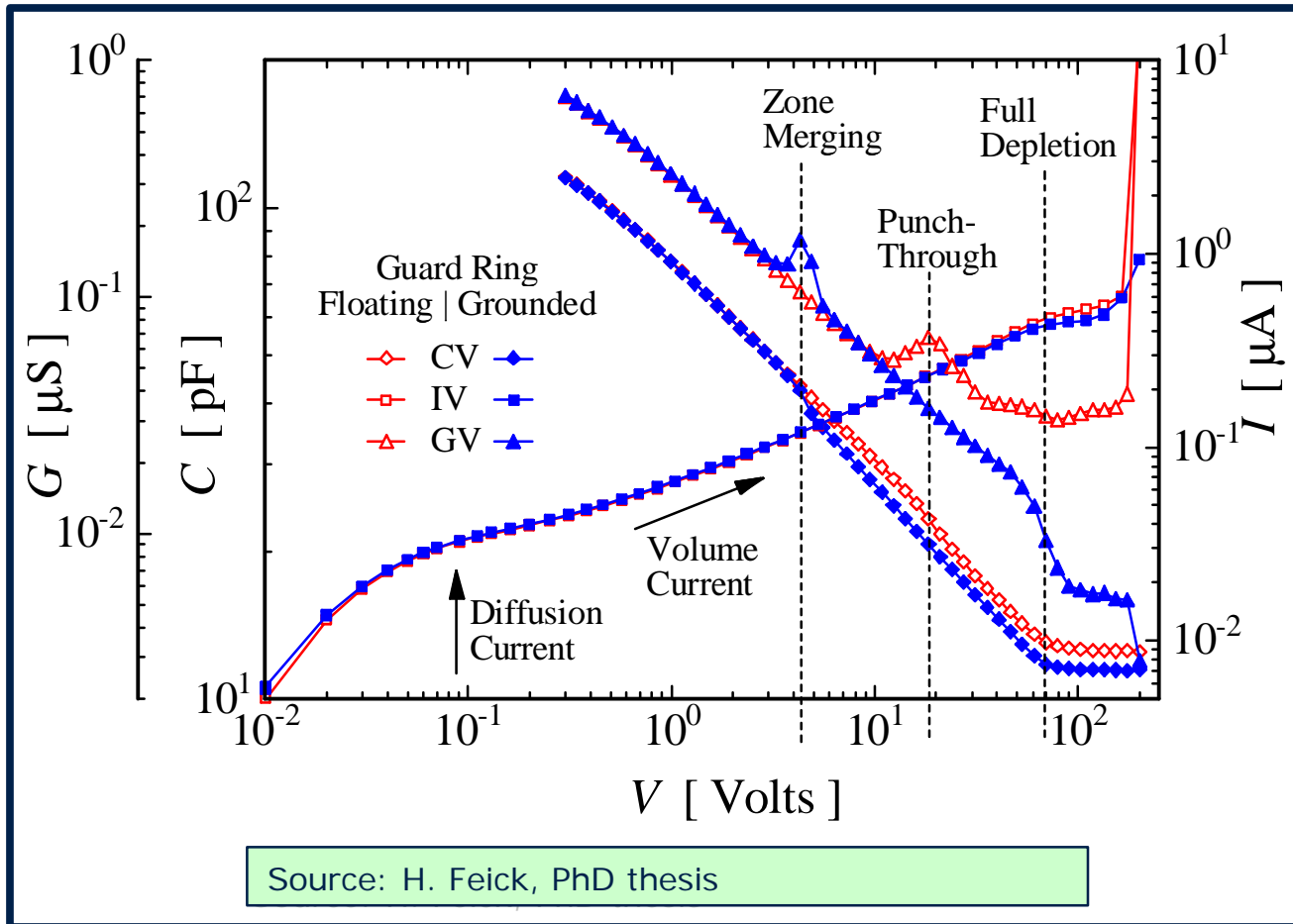
A lot of space is needed for isolating high voltages.

An area-saving technology requires careful optimization of the edge termination. This is often more difficult than the actual core device development.

Core device cross section considered in the TCAD simulations shown so far.

Lessons Learnt at "Nukleare Meßtechnik"

Edge Effects in Silicon Detectors

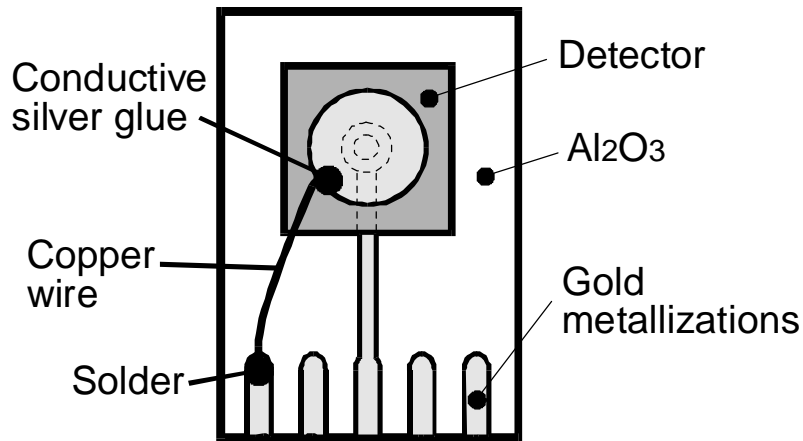


Although problems relating to diodes are rarely regarded as sufficiently appealing for a publication, mastering edge terminations and bipolar effects is considered a high art.

And Silicon detectors were my first steps in this direction.

Lessons Learnt from Gunnar: Part 2

Goal Orientation and Risk Awareness



Let's just copy the BNL sample holder – it does a perfectly good job for them!

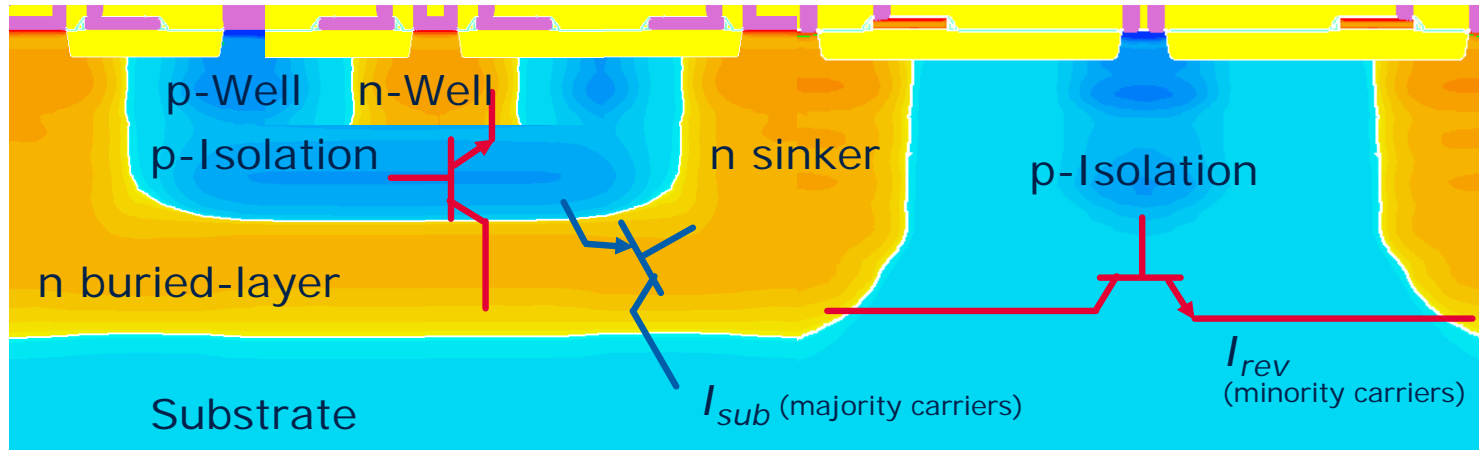
a) Reaching a goal is often much easier by copying a working solution from somebody else – this is very much true for the semiconductor industry.

b) Even barely noticeable details can endanger the entire project: Gunnar went to long ends to determine that the center line resistance to the backplane contact would be too high for high-frequency capacitance measurements. The layout was thus adjusted, the investment secured 😊.

There might be a little bit of over-engineering at work here, which is not so commonplace anymore, though.



Latch-up Risks in HV Technologies



Power switching can introduce significant substrate noise, especially if inductive loads are driven

- > reverse current when minority carriers are injected (n-type region drops below substrate ground potential)

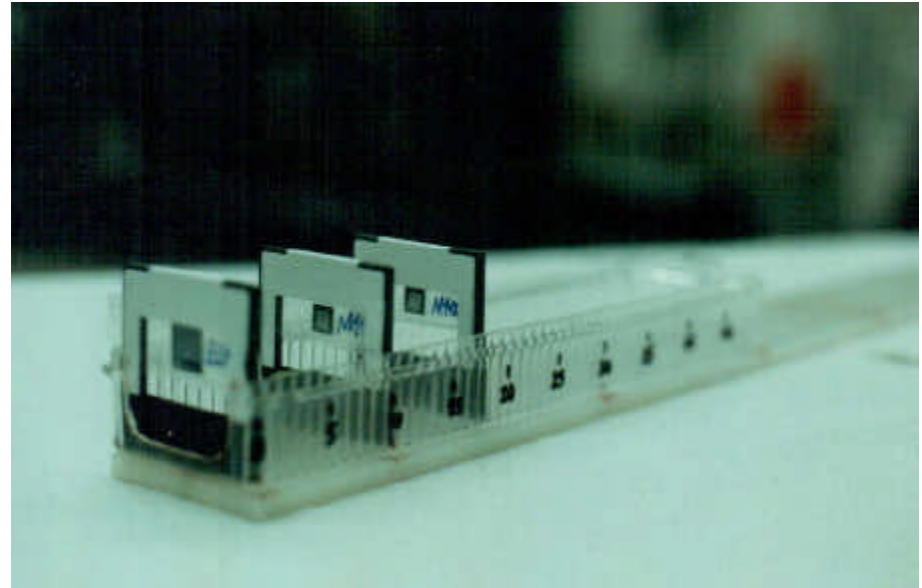
- > substrate currents when forward-biased p-n junction injects majority carriers into the substrate causing substrate potential variations

High-voltage isolation requires many parasitic bipolar paths to be minimized since they could potentially lead to latch-up problems.

Lessons Learnt from Gunnar: Part 3

Soft Skills: Dealing With Personnel

Well, well, there will be a lot of neutron scattering from this sample holder... But have it your way, for heaven's sake.



Yes, true, the neutron dose was probably a little off. But then, the radiation meter wouldn't show anywhere nearly as crazy numbers as for the old Aluminum sample holder, with all its bolts and nuts.

In order to avoid mutiny, it is always a good idea to listen and react to the wishes of your personnel – this is very much true for a company with many levels of hierarchy.



Developments for radiation hard silicon detectors by defect engineering—results by the CERN RD48 (ROSE) Collaboration^{*,**}

G. Lindström^{a,*}, M. Ahmed^b, S. Albergo^c, P. Allport^d, D. Anderson^e, L. Andric^f, M.M. Angarano^g, V. Augelli^h, N. Bacchettaⁱ, P. Bartoliniⁱⁱ, R. Bates^j, U. Biggeri^k, G.M. Bilei^l, D. Bisello^m, D. Boemiⁿ, E. Borchini^o, T. Botila^p, T.J. Brodbeck^q, M. Bruzzi^r, T. Budzynski^s, P. Burger^t, F. Campabadal^{u,v}, G. Casse^w, E. Catacchini^x, A. Chilingarov^y, P. Ciampolini^z, V. Cindro^{aa}, M.J. Costa^{ab,ac}, D. Creanza^{ad}, P. Clauws^{ae}, C. Da Via^{af}, G. Davies^{ag}, W. De Boer^{ah}, R. Dell'Orso^{ai}, M. De Palma^{aj}, B. Dezillie^{ak}, V. Eremin^{al}, O. Evrard^{am}, G. Fallica^{an}, G. Fanourakis^{ao}, H. Feick^{ap}, E. Focardi^{aq}, L. Fonseca^{ar,as}, E. Fretwurst^{at}, J. Fuster^{au,av}, K. Gabathuler^{aw}, M. Glaser^{ax}, P. Grabiec^{ay}, E. Grigoriev^{az}, G. Hall^{ba}, M. Hanlon^{bb}, F. Hauler^{bc}, S. Heising^{bd}, A. Holmes-Siedle^{be}, R. Horisberger^{bf}, G. Hughes^{bg}, M. Huhtinen^{bh}, I. Ilyashenko^{bi}, A. Ivanov^{bj}, B.K. Jones^{bk}, L. Jungermann^{bl}, A. Kaminsky^{bm}, Z. Kohout^{bn}, G. Kramberger^{bo}, M. Kuhnke^{bp}, S. Kwan^{bq}, F. Lemeilleur^{br}, C. Leroy^{bs}, M. Letheren^{bt}, Z. Li^{bu}, T. Ligonzo^{bv}, V. Linhart^{bw}, P. Litovchenko^{bx}, D. Loukas^{by}, M. Lozano^{bz}, Z. Luczynski^{ca}, G. Lutz^{cb}, B. MacEvoy^{cc}, S. Manolopoulos^{cd}, A. Markou^{ce}, C. Martinez^{cf,ag}, A. Messineo^{ch}, M. Miku^{ci}, M. Moll^{ck}, E. Nossarzewska^{cl}, G. Ottaviani^{cm}, V. Oshea^{cn}, G. Parrini^{co}, D. Passeri^{cp}, D. Petre^{cq}, A. Pickford^{cr}, I. Pintilie^{cs}, L. Pintilie^{ct}, S. Pospisil^{cu}, R. Potenza^{cv}, V. Radicci^{ch}, C. Raine^{ci}, J.M. Rafi^{ck,cl}, P.N. Ratoff^{cm}, R.H. Richter^{cn}, P. Riedler^{co}, S. Roe^{cp}, P. Roy^{cq}, A. Ruzin^{cr}, A.I. Ryazanov^{cs}, A. Santocchia^{cd}, L. Schiavulli^{ce}, P. Sicho^{cf}, I. Siotis^{cg}, T. Sloan^{ch}, W. Slysz^{ci}, K. Smith^{cl}, M. Solanky^{cm}, B. Sopko^{cn}, K. Stolze^{co}, B. Sundby Avset^{cp}, B. Svensson^{cq}, C. Tivarus^{cr}, G. Tonelli^{cs}, A. Tricomi^{ct}, S. Tzamarias^{cu}, G. Valvo^{cv}, A. Vasilescu^{cw}, A. Vayaki^{cx}, E. Verbitskaya^{cy}, P. Verdini^{cz}, V. Vrba^{ca}, S. Watts^{cb}, E.R. Weber^{cc}, M. Wegrzecki^{cd}, I. Wegrzecka^{ce}, P. Weilhammer^{cf}, R. Wheadon^{cg}, C. Wilburn^{ch}, I. Wilhelm^{ci}, R. Wunstorff^{ck}, J. Wüstenfeld^{cl}, J. Wyss^{cm}, K. Zankel^{cn}, P. Zabierowski^{co}, D. Zontar^{cp}

^{*}Presented at the LEB workshop Cracow, September 2000, see CERN report CERN 2000-010 CEIN/LHCC/2000-04.

^{**}Corresponding author. Tel.: +49-40-8998-2951; fax: +49-40-3998-2950.

E-mail address: gumar@ssun.de (G. Lindström).

Lessons Learnt from Gunnar: Part 4 Leadership

Forming coalitions, joining forces, motivating people, and taking the leading role is key to a successful career.

And Gunnar has always been a true master at this.





Thank you.

Infineon Dresden
Quality meets
Innovation.

Broad Technology Base

Prime Security Standards

Fast Customer Samples

Advanced Automation

Customer Embedded

High Flexibility

Rapid Ramps

Zero Defect

Top Experts

Open Mindset

More than Moore

World Class Yields

Short Cycle Times



Never stop thinking



ENERGY EFFICIENCY MOBILITY SECURITY

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